



Isotropic Electrically Conductive Adhesives

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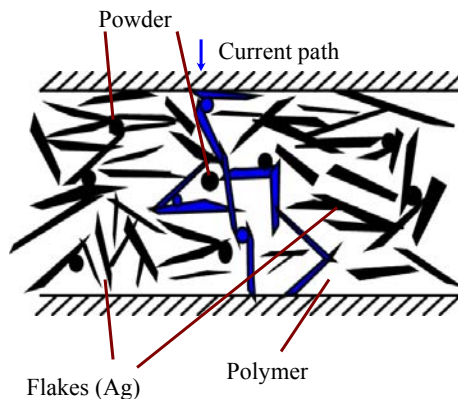
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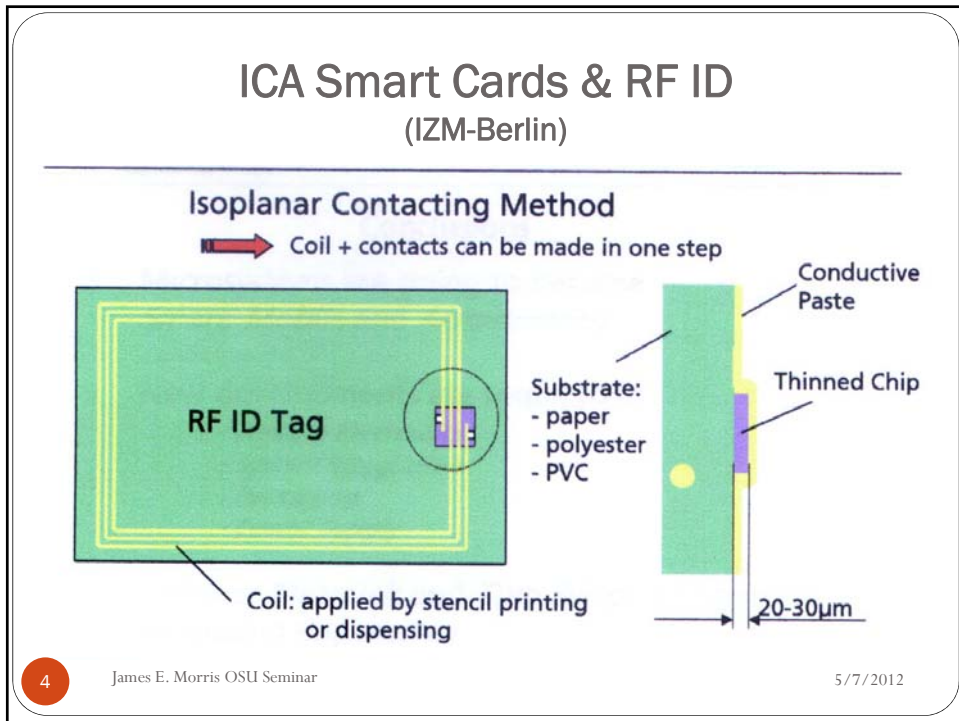
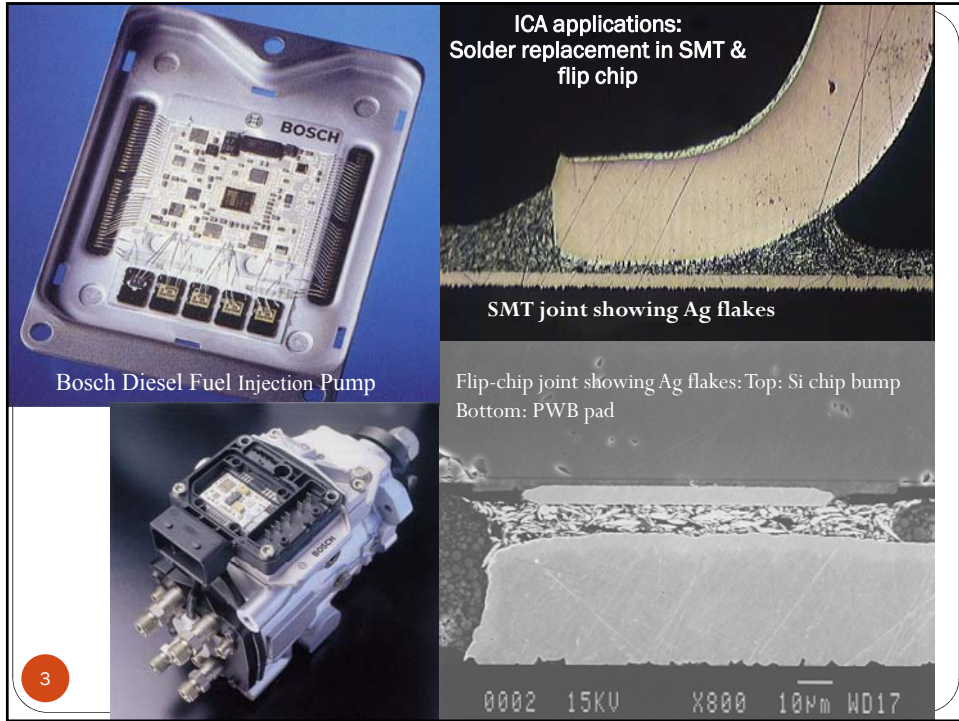
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ICA: Isotropic Conductive Adhesives



Contents

- Introduction
 - Applications
 - Processing
- Resistance & measurement
- Nanotechnology
- Layering effect
- Adhesion
- Drop test
- Galvanic corrosion
- Cure models
- Miscellaneous



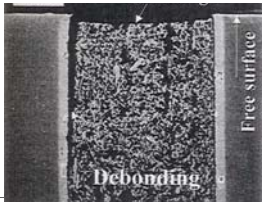
ICA Microvias: Ag, Cu, & LMP (Low Melting Point) Alloy

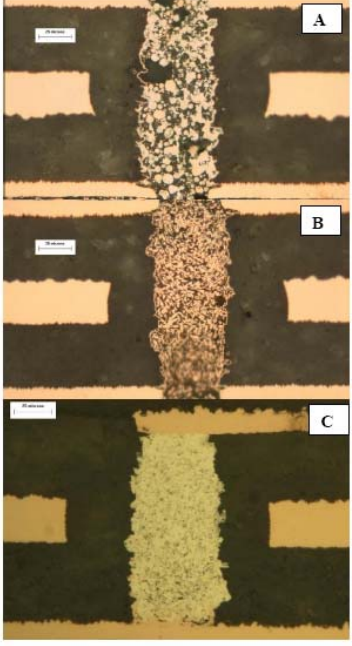
[Das et al (Endicott Interconnect), ECTC'06]

Adhesive	90 Degree Peel strength (lbs/inch)	Tensile Strength (PSI)	Failure Mode
Low melting point (LMP) Alloy	1	600	Cohesive
Copper (Cu)	1.77	Cohesive	
Silver (Ag)	2.75	3370	Cohesive

Table 1: 90 degree peel-strength and tensile strength of adhesives

Failure modes →





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Figure 8: Adhesive-filled joining cores (A) LMP, (B) Cu, and (C) silver

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(Sintered NanoParticle) ICA Die Attach

[Bai et al (VaTech), HDP'05]

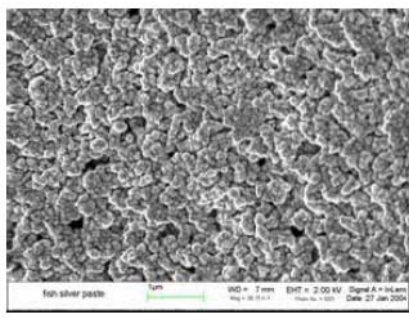


Fig. 2. SEM images of the nanoscale silver on a silic substrate after sintering at 280°C for 10 mins.

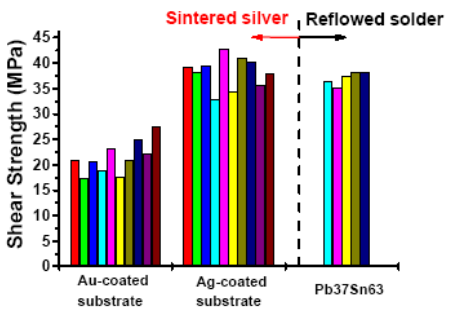


Fig. 8. The comparison of the shear strength of the low-temperature silver-sintering with solder reflow.

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ACA: Anisotropic Conductive Adhesive (& ACF)

Labels: Adhesive, IC, Bump, Glass substrate, Electrode, Conductive particles

Scale: 20µm

Labels: Silicon chip, 4 microns, Aluminium metallisation, Adhesive, Conductive particle, Gold/nickel plate, Copper metallisation

Ni particle

Labels: Si chip, Adhesive, Au plated Ni layer, Copper on flex

Coated polymer particle

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Technology Drivers

- **Environment**
 - **Environmental:**
 - - No-flux, no-Pb
 - **No-Pb solders**
 - -Melting temperatures
 - -Thermomechanical stress
 - **Silver effects**
- **Economics**
 - **Manufacturing**
 - Fewer process steps
 - Available technologies (stencil/screen/dispense)

- **Technology drivers (c.f. solder)**
 - **Thermomechanical stress**
 - Low process temperature
 - High compliance
 - **Fine-pitch (area array) interconnect**
 - Smaller particles than solder
 - No slumping
 - Inter-metallic diffusion in solders
 - Electromigration

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Processing e.g. Flip-Chip Assembly (IZM, Berlin)

Isotropic Conductive Adhesive

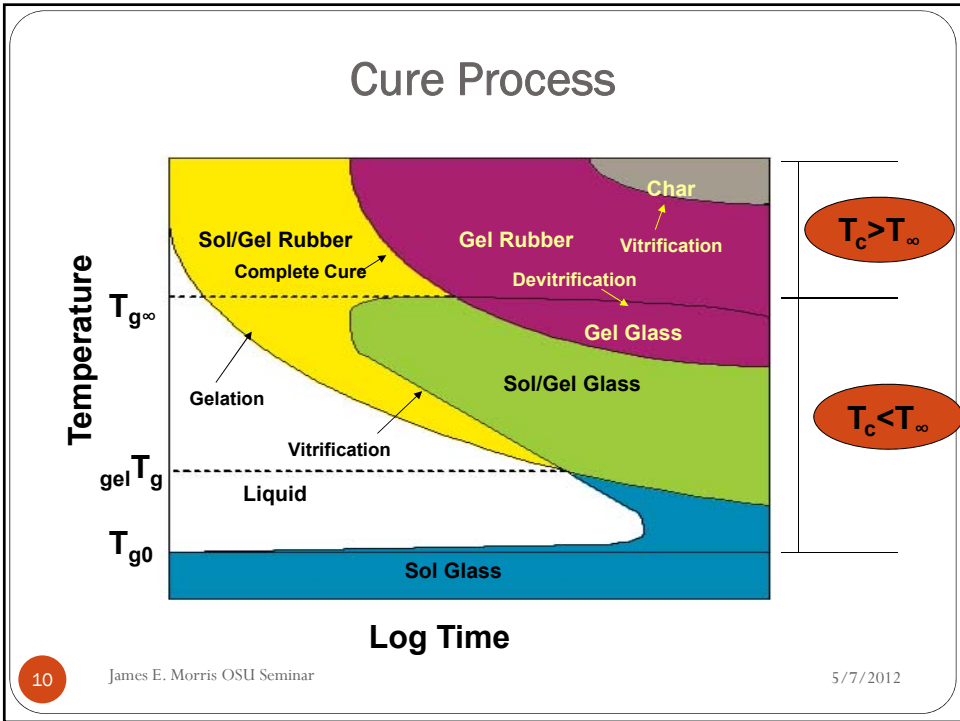
Anisotropic Conductive Adhesive

Non-Conductive Adhesive

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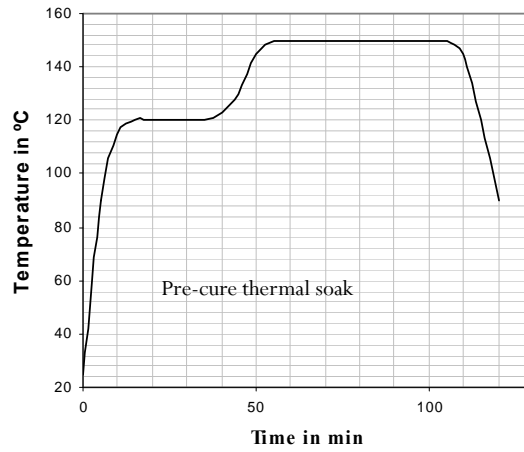
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Thermal Cure: Optimization

Typical specification:
 Temperature T
 and time t
 Probably a range
 of T & t
 combinations
 Possibly ramp
 rates dT/dt



Cure Effects

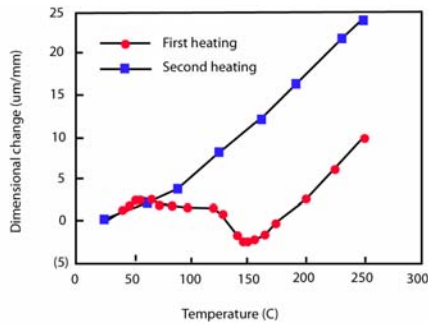


Figure 1. Dimensional change of conductive adhesive

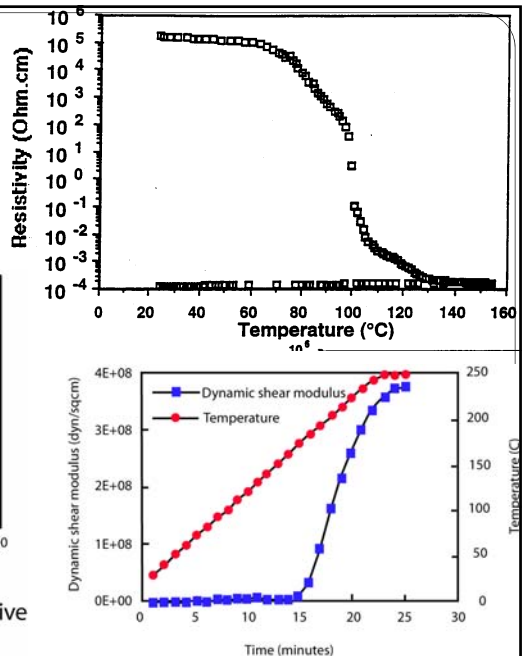


Figure 2. Dynamic shear modulus of conductive adhesive during cure

Properties Commonly used isotropic conductive adhesives (Jagt, Chapter 11, Conductive adhesives for Electronics Packaging)

Adhesive & Type	Viscosity (Pa.s)	Potlife	Glass transition	Volume Resistivity Ωcm	Shear strength (MPa)	Curing time (min.)	Curing Temp. ($^{\circ}\text{C}$)
ICA 1 (1 comp.)	65	3 days	80	$2 \cdot 10^{-4}$	11	10-15	130-150
ICA 2 (2 comp.)	25-35	3-4 days	85	$1-4 \cdot 10^{-4}$	10	30	130-140
ICA 3 (2 comp.)	50	2 days	50	$2-4 \cdot 10^{-5}$	8	90	130-140
ICA 4 (1 comp.)	160-200	4 days	80	$5 \cdot 10^{-3}$	5	20-30	120-130
ICA 5 (1 comp.)	310-350	4 days	80	$1 \cdot 10^{-3}$	4	20-30	120-130
ICA 6 (2 comp.)	150-200	8-12 hr	75	$2-5 \cdot 10^{-4}$	14	10-15	170-180

Compare intrinsically conducting polymers,
 e.g. Polyaniline: $\rho = 10^5$ (intrinsic) to $10^{-2} \Omega\text{.cm}$ (doped)
 Compare Ag: $\rho_{\text{Ag}} = 1.6 \times 10^{-6} \Omega\text{.cm}$; $\rho_{\text{ICA}} = 12.5$ to $312.5 \times \rho_{\text{Ag}}$

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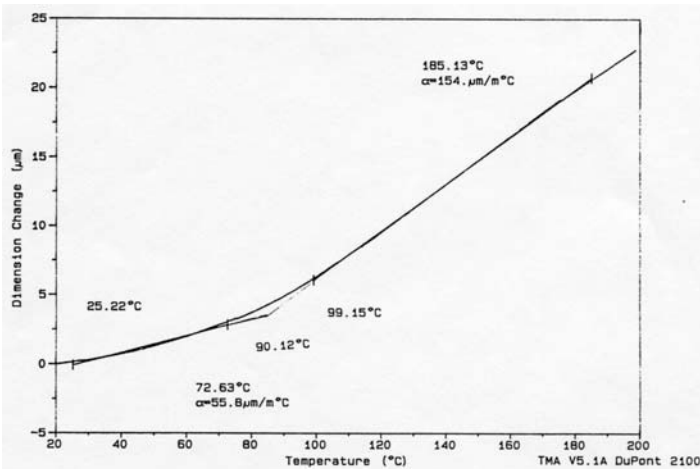
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Glass Transition Temperature

Table 4.3. TMA experimental results for cured block samples.

Materials	T_g ($^{\circ}\text{C}$)	CTE ($<T_g$) ($\mu\text{m}/\text{m}^{\circ}\text{C}$)	CTE ($>T_g$) ($\mu\text{m}/\text{m}^{\circ}\text{C}$)
Adhesive A	90	56	155
Adhesive B	90	61	168
Adhesive C	90	78	218



Compare CTEs:
 Si = 4-5 ppm/ $^{\circ}\text{C}$
 Ag = 20 ppm/ $^{\circ}\text{C}$
 Epoxy = 54 ppm/ $^{\circ}\text{C}$
 FR4 = 36 ppm/ $^{\circ}\text{C}$

Figure 4.4: Typical TMA graphs for Adhesive A showing CTE above and below T_g .

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Low Resistance Measurement

(a) (b)

(c) $R_{meas} = 16R + R_{leads}$

(d) (e)

1:N $N^2 R$

Wheatstone bridge

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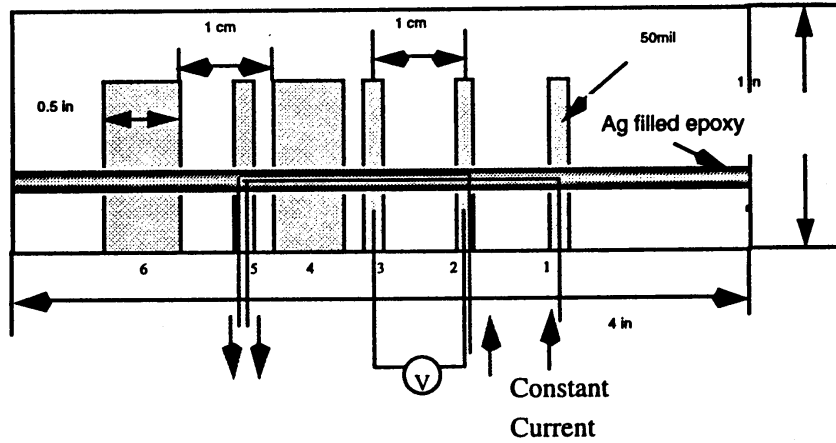
Electrical Test: Four-terminal measurement

(a) (b) Kelvin probe

(c)

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Three terminal measurement for pad contact resistance

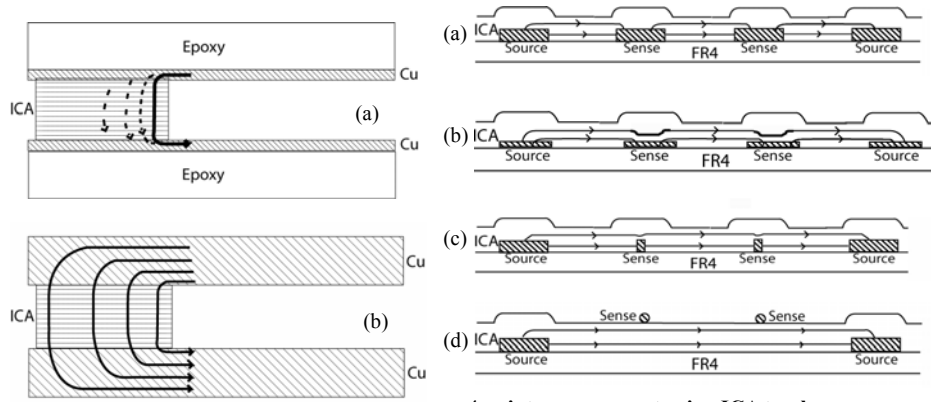


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Current crowding & contact shorting



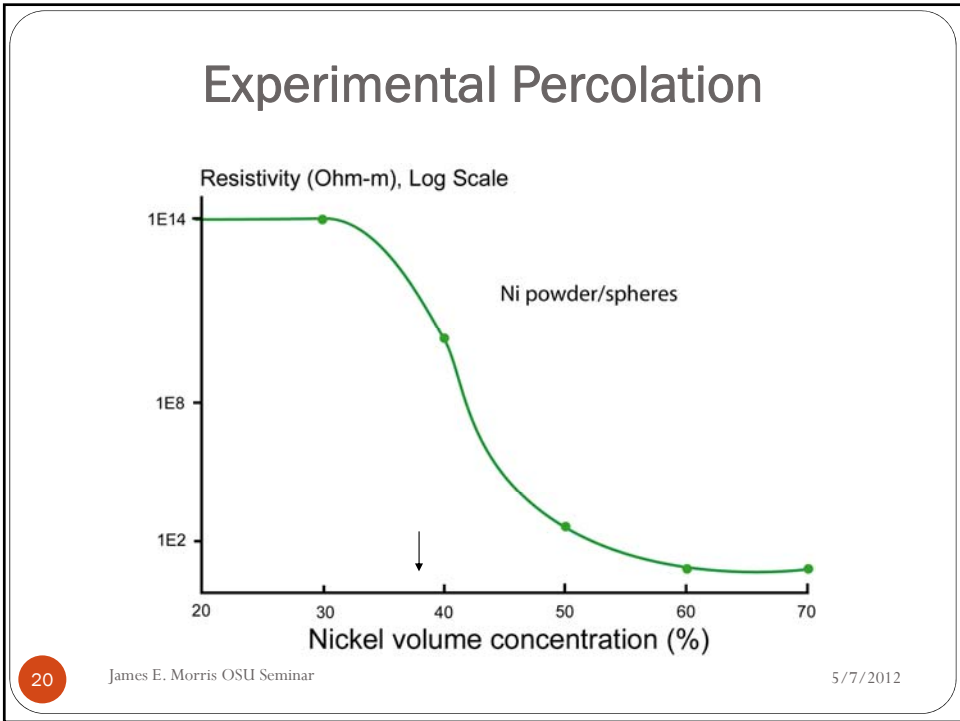
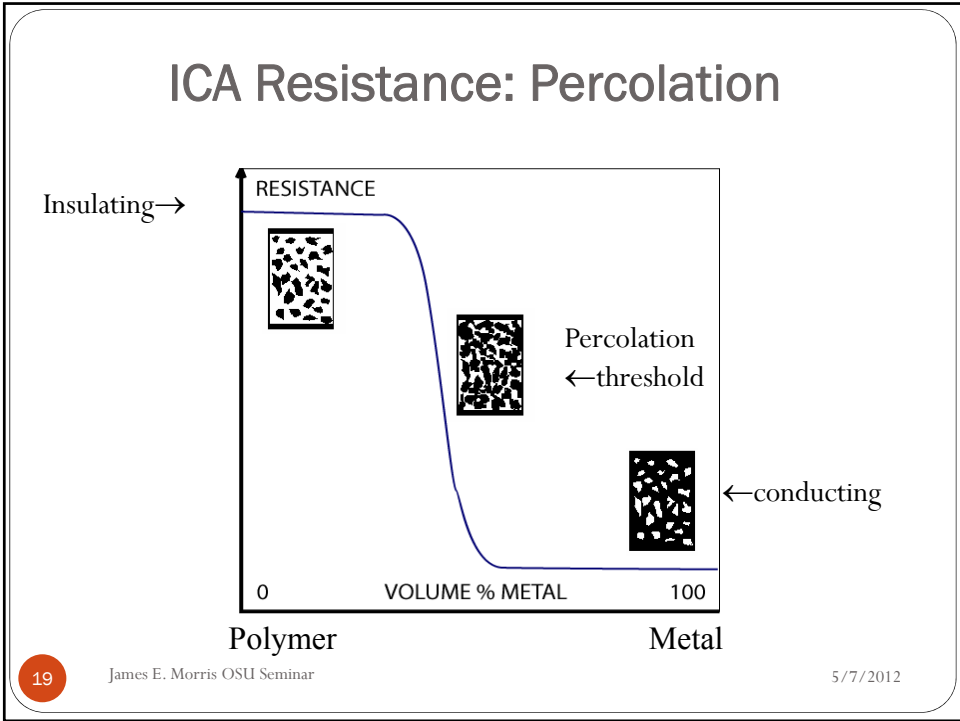
- (a) Current Crowding
- (b) Equally Distributed Current

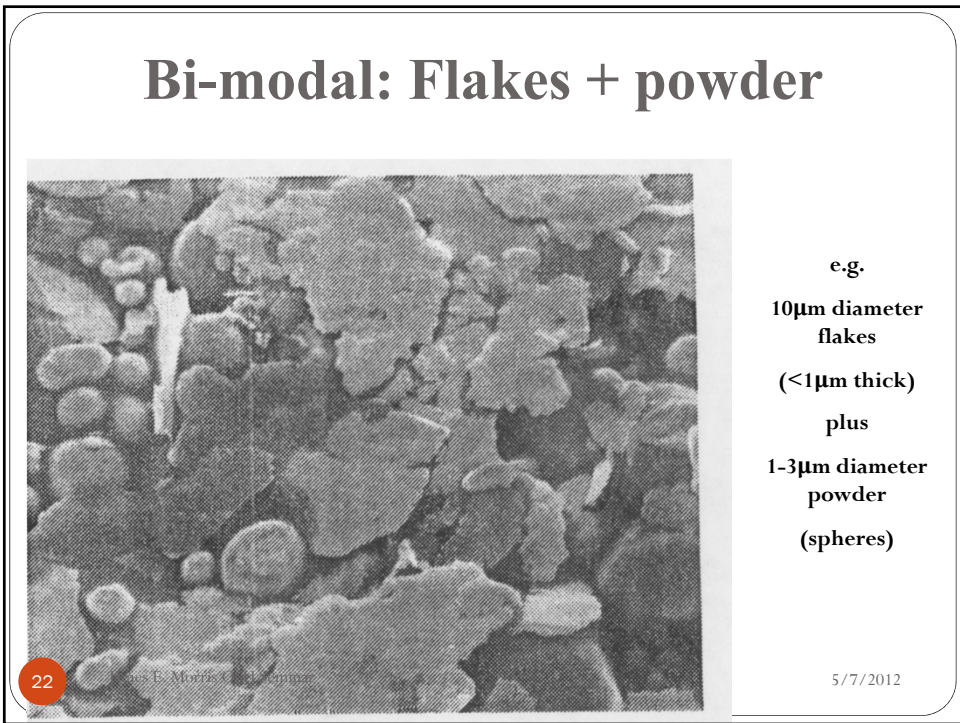
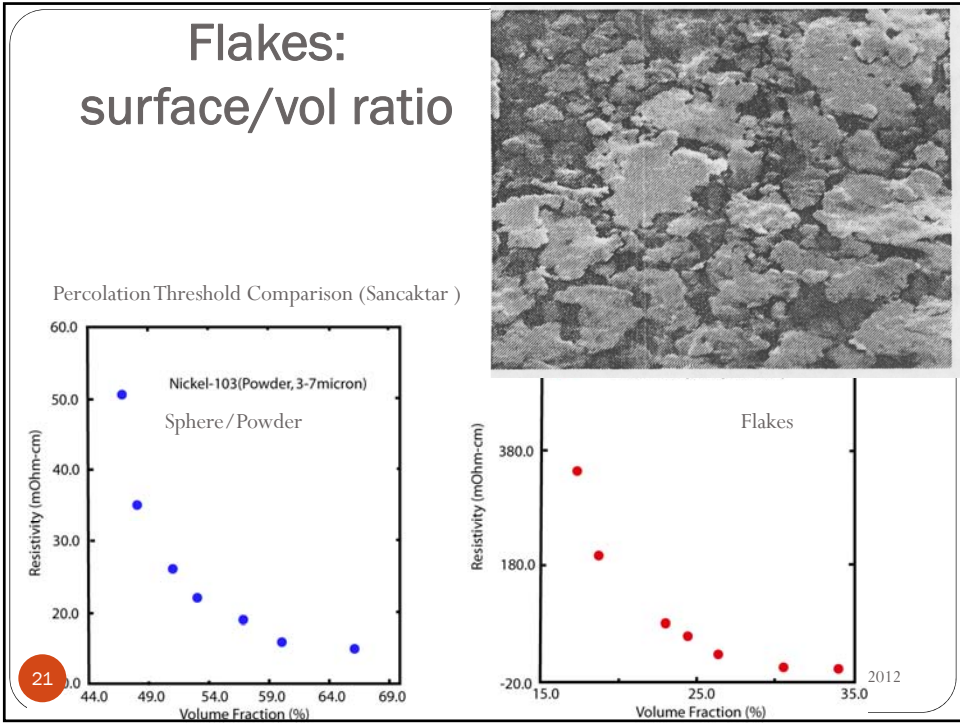
- 4-point measurement using ICA track across proto-board current lines
- (a) Sense lines short ICA
- (b) thinned contacts
- (c) trimmed contacts
- (d) Surface point contacts

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ECA Resistance

ICA Resistance

- Percolation
- Particle
 - μm particles
 - 10^2 's nm e⁻ mfp
 - Negligible size effects
- Inter-particle
 - And pad contact
- Experimental
- (Modeling)

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Monte Carlo Percolation Models

$p = 0.1$

a)

$p = 0.3$

b)

$p = 0.5$

c)

$p = 0.6$

d)

$p = 0.7$

e)

Percolating cluster

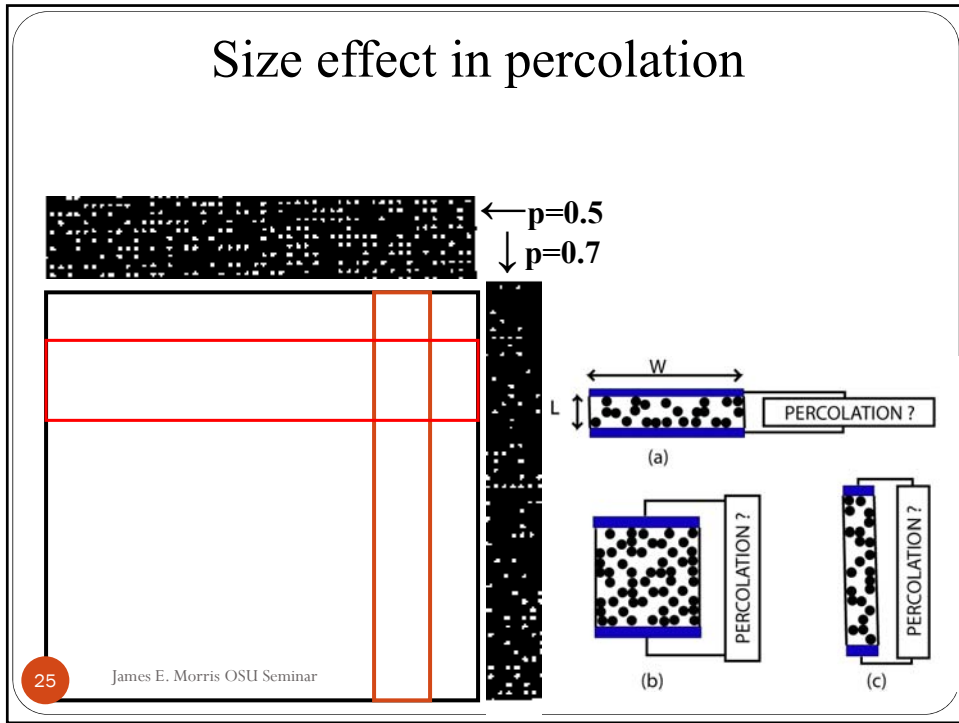
f)

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(Smilauer) 5/7/2012

Size effect in percolation

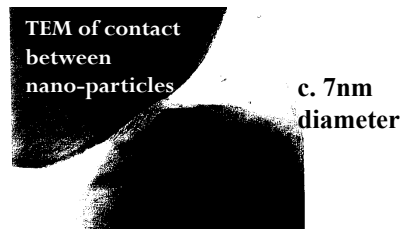
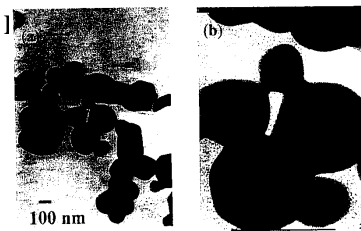
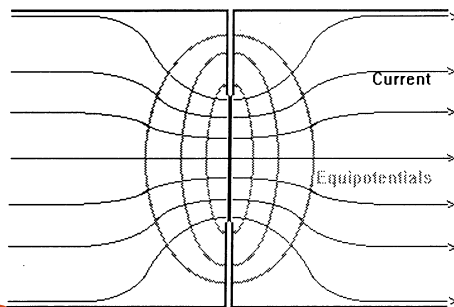


Particle Contact Resistance

Constriction resistance:

$$\rho / 2a$$

- Current crowding
- Circular contact
- Diameter $2a$



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Polymer/Insulating Oxide

- Thermionic emission (with Schottky effect)
- Electron tunneling (with image effect)
- Poole-Frenkel emission
- Fowler-Nordheim tunneling

- $TCR \leq 0$ & field effects for various mechanisms
- None of these observed

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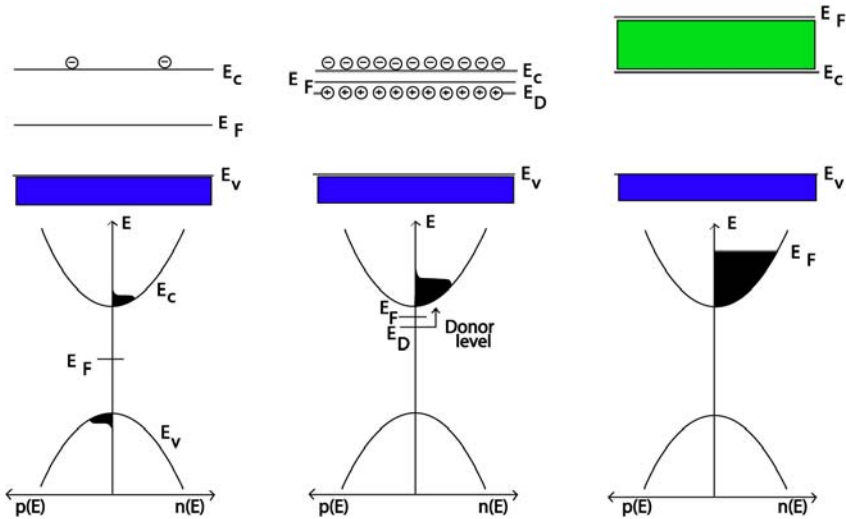
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AgO/Ag₂O Degenerate Semiconductor

Intrinsic

Extrinsic

Degenerate

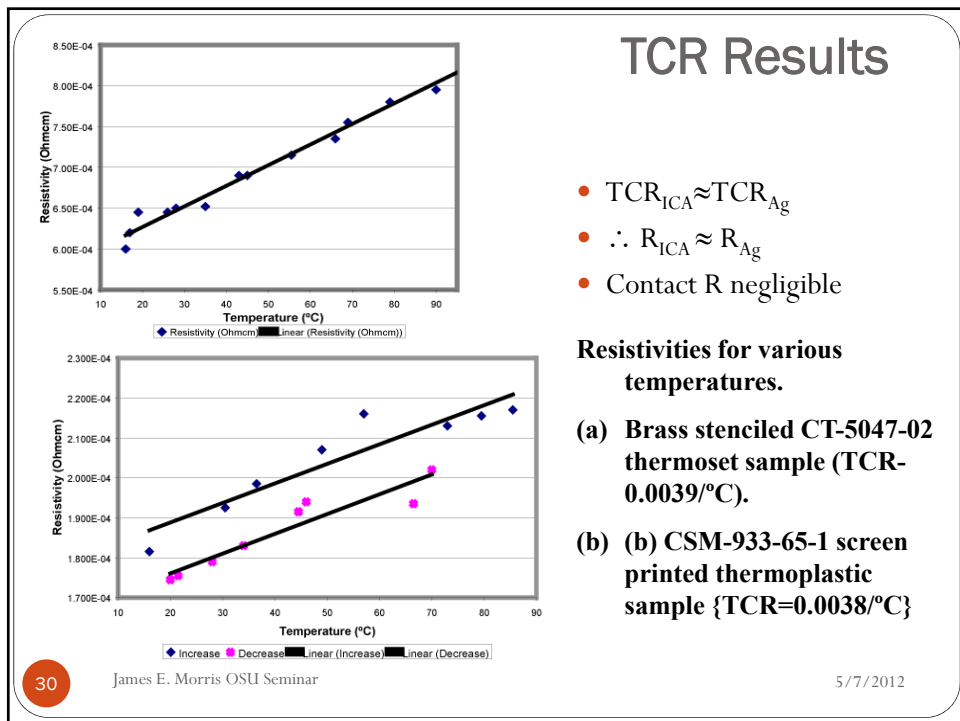
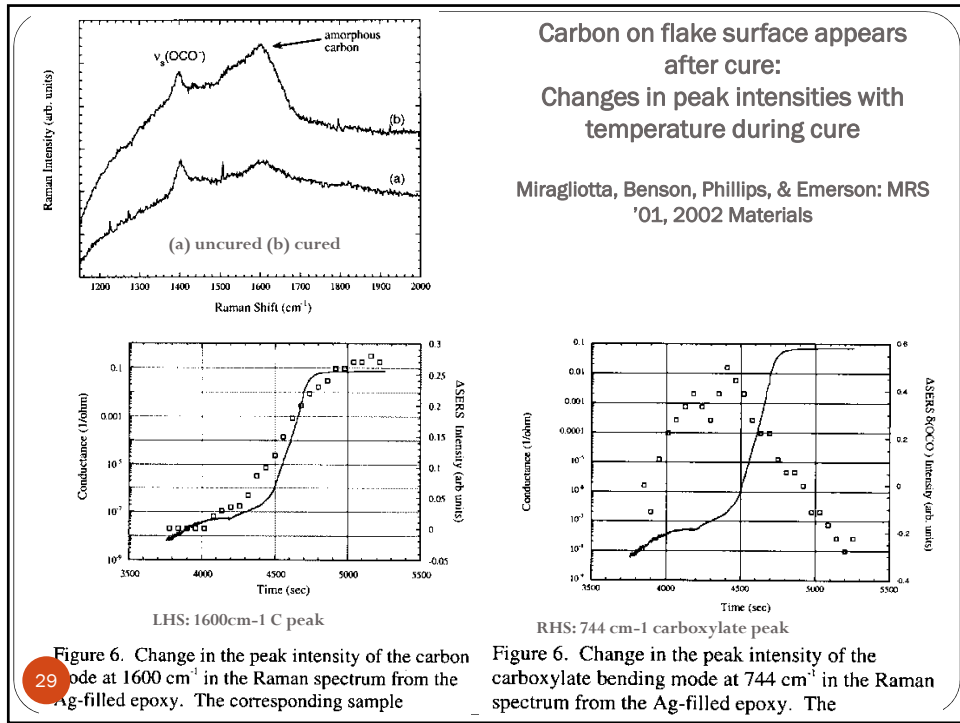


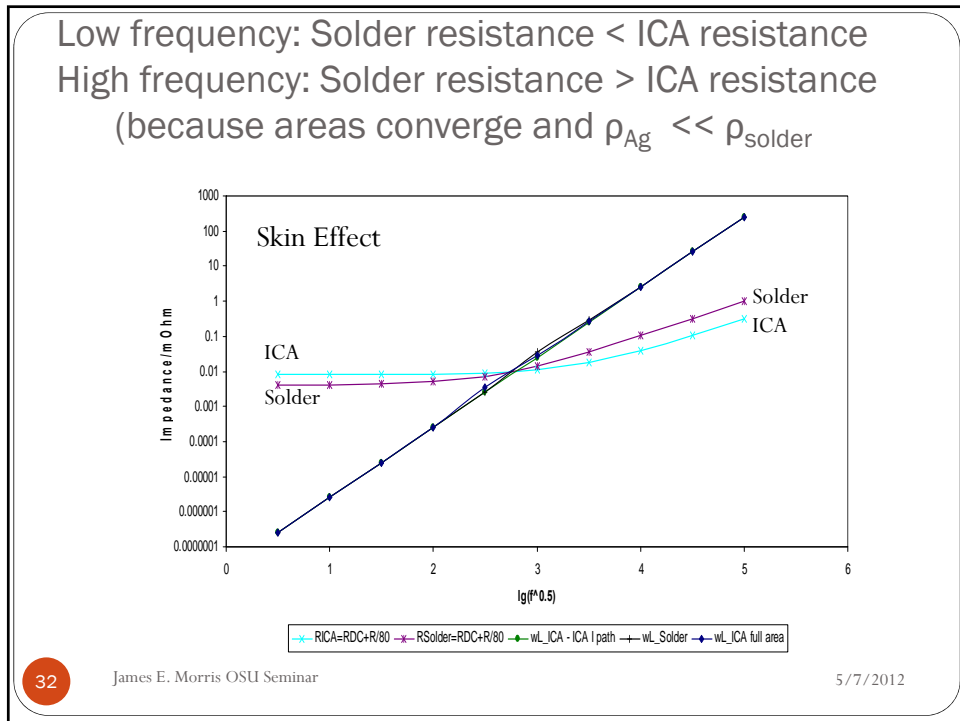
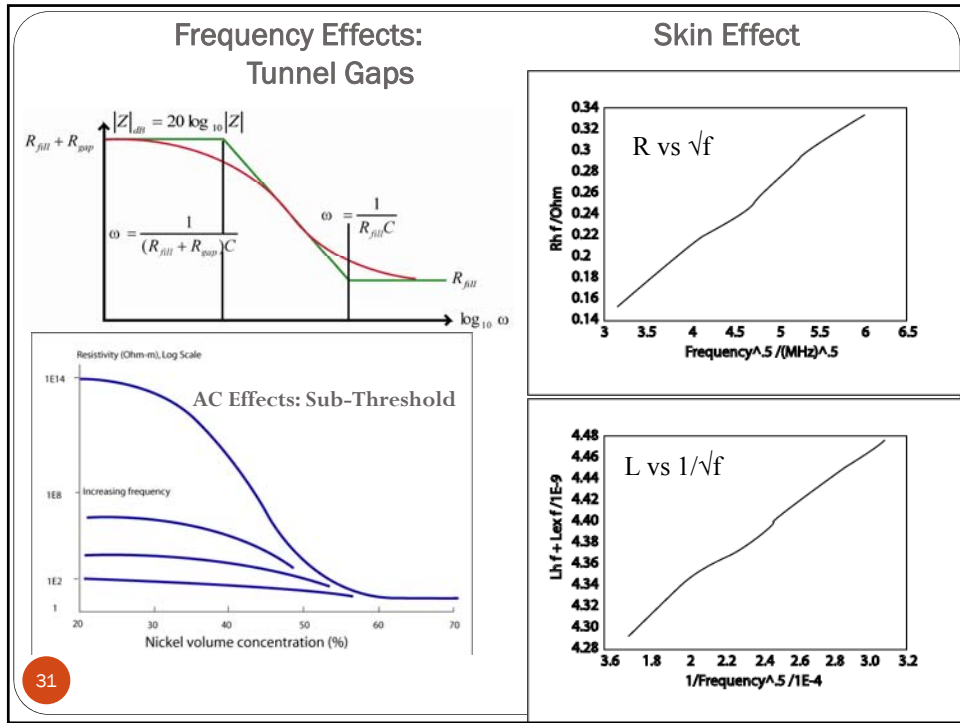
Silver oxide (degenerate semiconductor) Also $\propto 1/a^2$

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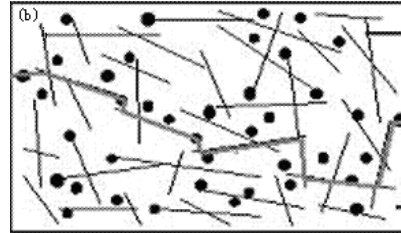
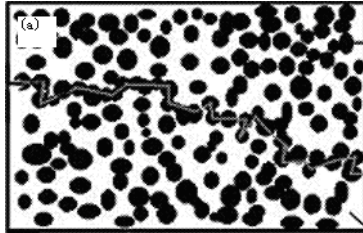
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Nanotechnologies, e.g. Add CNTs



Electrically conductive fillers with CNT

Negligible effect

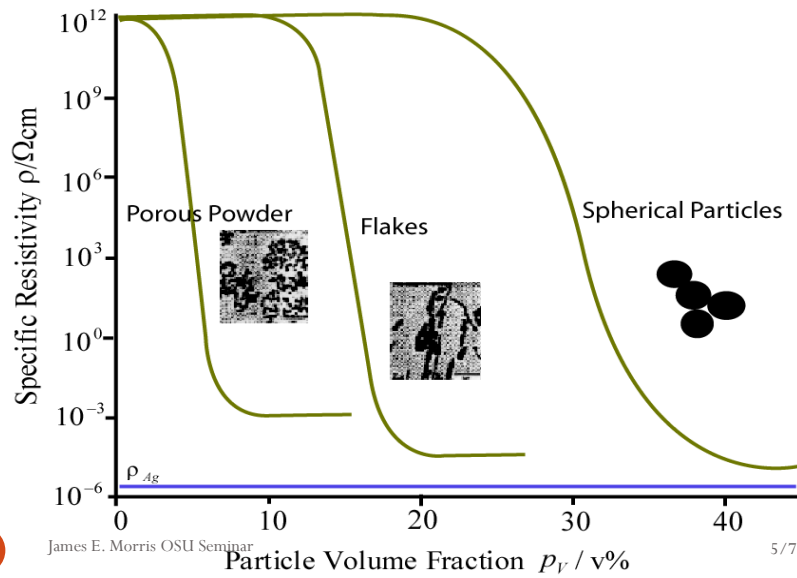
(Courtesy Prof. Zhaonian Cheng, SMIT Center, Shanghai University)

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Nanoparticles in Isotropic Conductive Adhesives (ICAs) (Stefan Kotthaus)



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[Wong et al, ECTC'06]

(a)

(b)

(c)

Nanoparticle Sintering

Figure 10. Side view of neck formation for particles of sizes 1014 and 2439 atoms.

Figure 12. Increase in number of atoms N in the neck region during sintering at 300 K and 800 K.

Raut, Bhagat, Fichthorn, Nanostruct. Mater. 10(5) 1998, 837-851

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Layering Effect

Fig. 3a Adhesive A, 900x magnification.

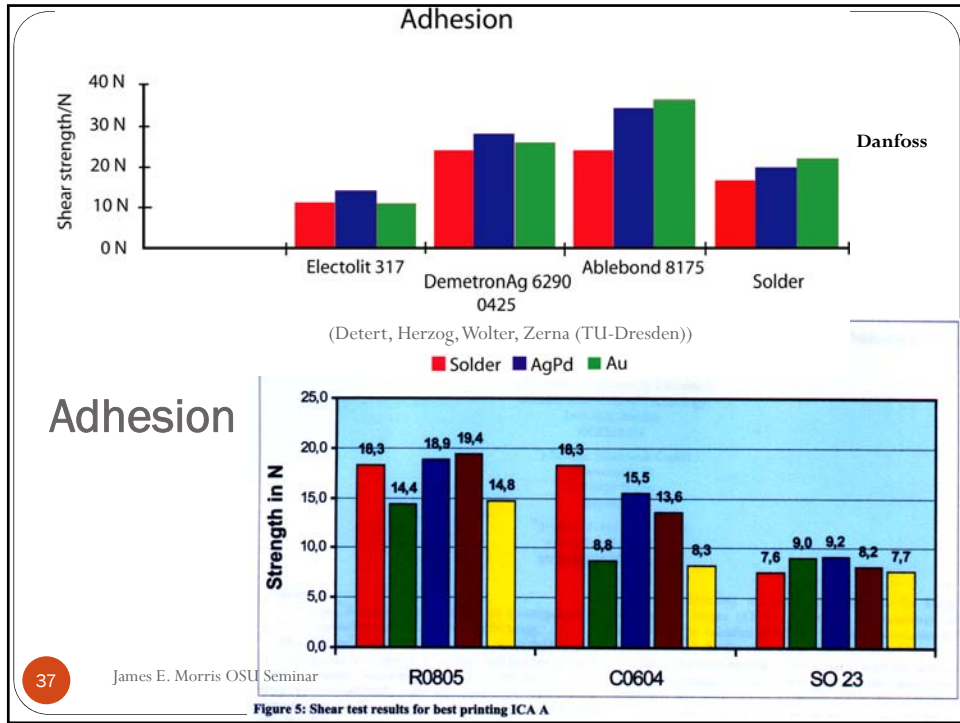
Constable et al (Adhesives'98)

Z-axis Size Effect Expt

Circuit board, ICA, Current density distribution, Hg, Cu, V

Resistivity

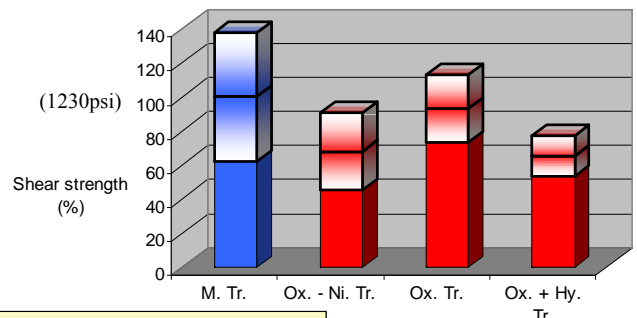
Resistivity as a function of the thickness.



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Shear test result with plasma treatment



Upper two columns show the standard deviation

M. Tr. - Mechanical treatment

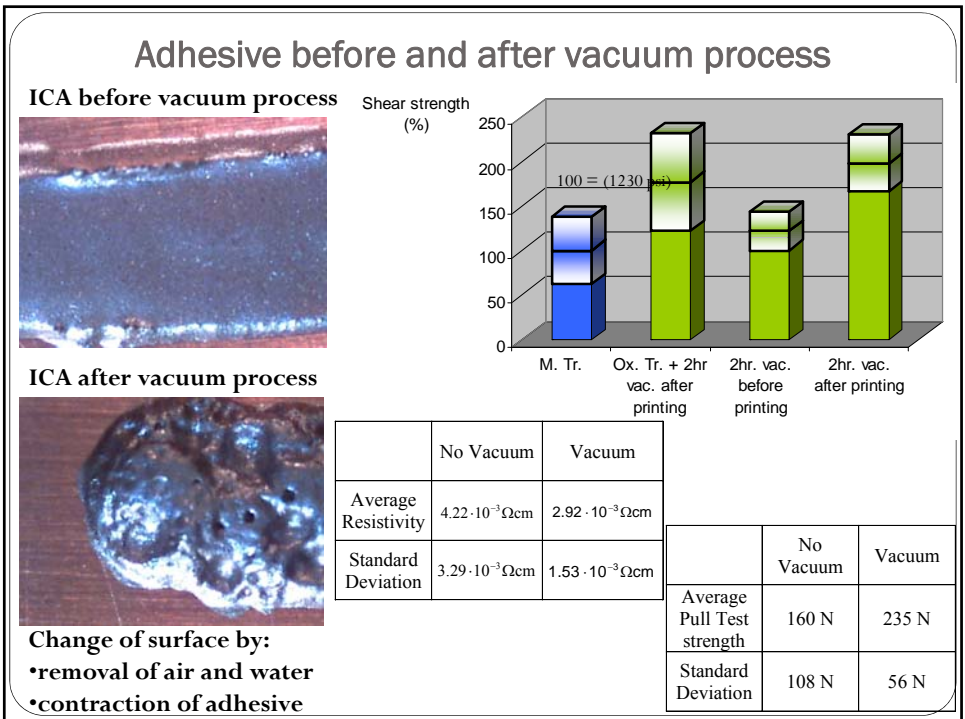
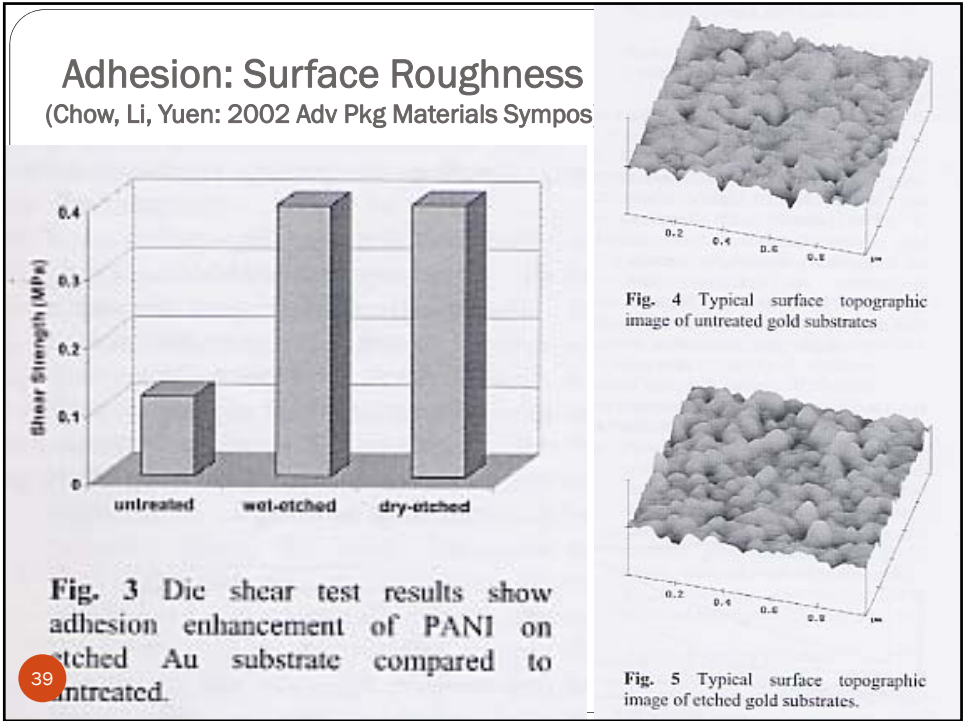
Ox. - Ni. Tr. - Oxygen Nitrogen treatment

Ox. Tr. - Oxygen treatment

Ox. + Hy. Tr. - First oxygen treatment then hydrogen treatment

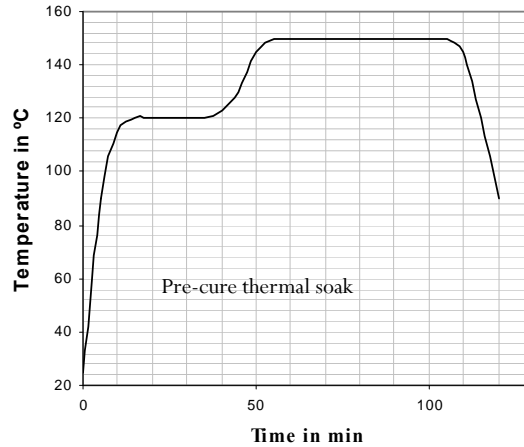
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Thermal Cure: Optimization

Typical specification:
 Temperature T and time t
 Probably a range of T & t combinations
 Possibly ramp rates dT/dt



Impact Strength/Drop Test (Tong)

- Adhesion tests passed
- Devices fall off PWB if dropped
 - Large devices fail; small OK
- No correlation between drop test results and adhesion strength testing
- Complex shear modulus
 - Storage and loss moduli

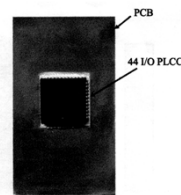


Figure 2. A Photograph of a Drop Test Sample

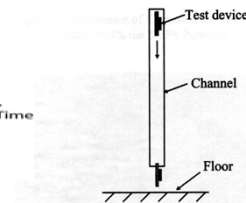
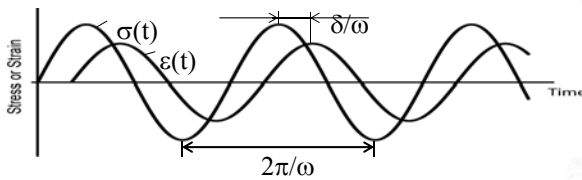
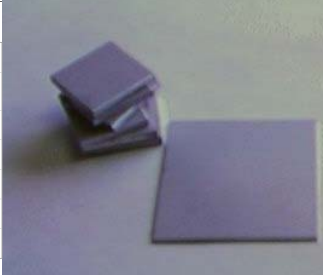

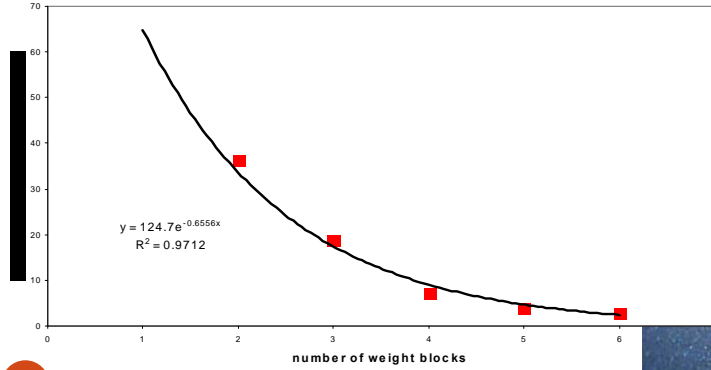


Figure 3. A Schematic of Drop Test Set-up

Variation with inertial mass

Blocks	Drops till failure
1	More than 120 (no failure)
2	30, 43
3	17, 21
4	7, 4, 11
5	4, 4
6	3



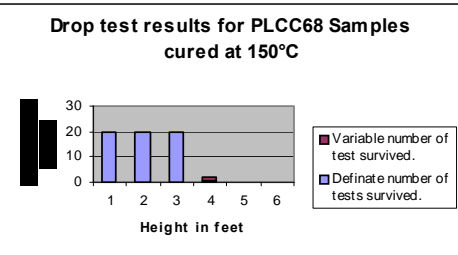
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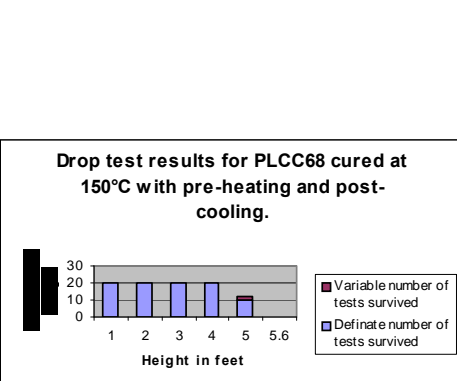
Multiple Drop Testing:

1. Cumulative damage
2. Pre-heat effects

Drop test results for PLCC68 Samples cured at 150°C



Drop test results for PLCC68 cured at 150°C with pre-heating and post-cooling.



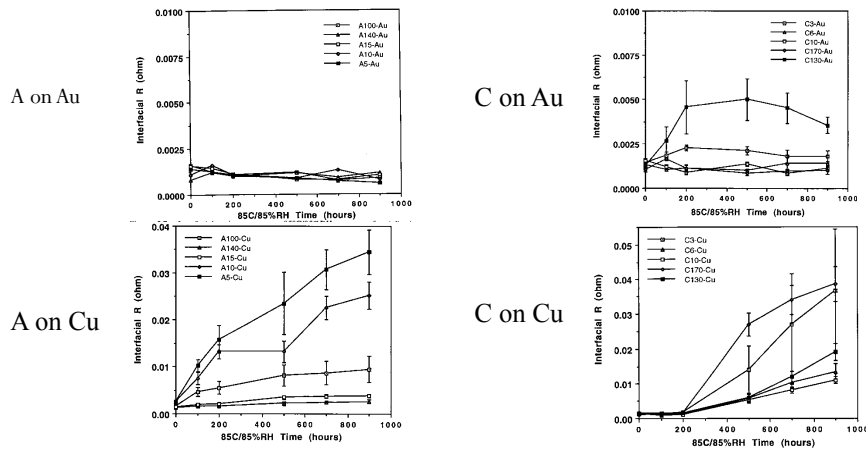
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Contact R 85°C/85% RH: Au & Cu contacts

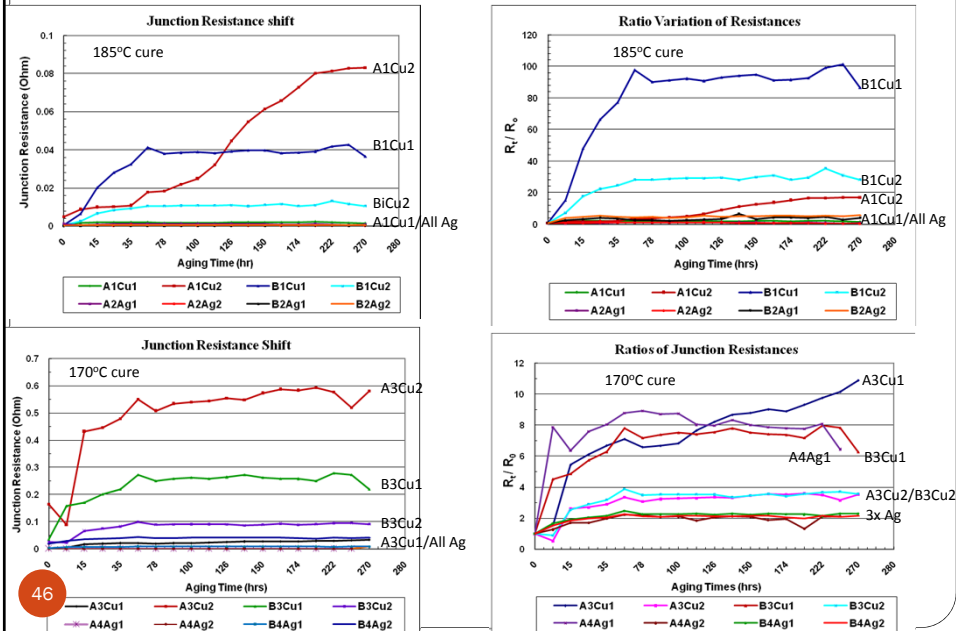
Galvanic Corrosion: Dissimilar metals + H₂O

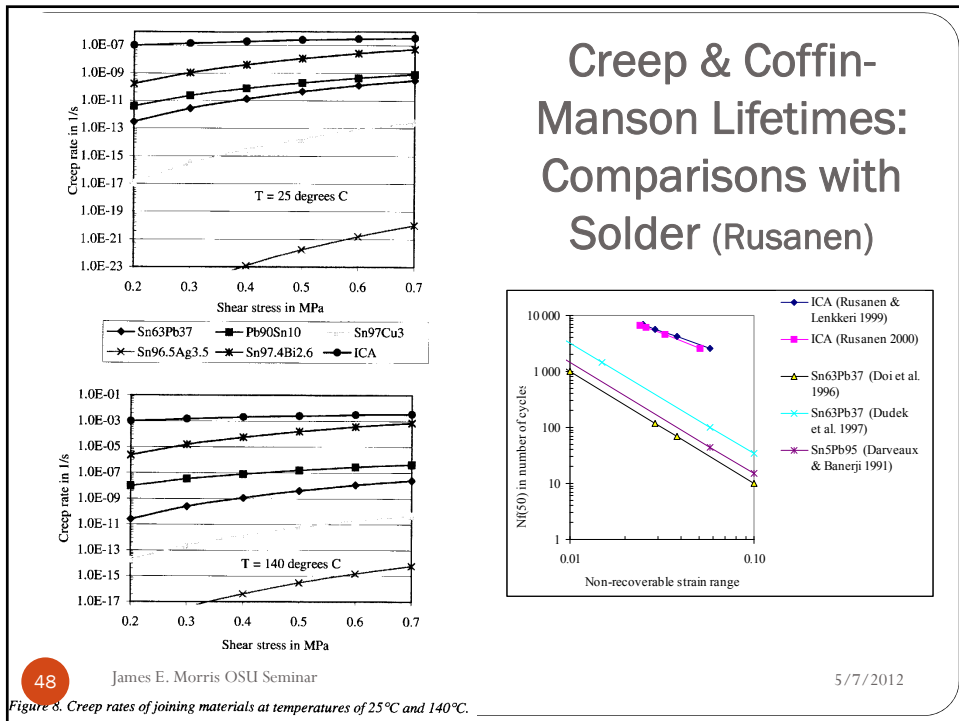
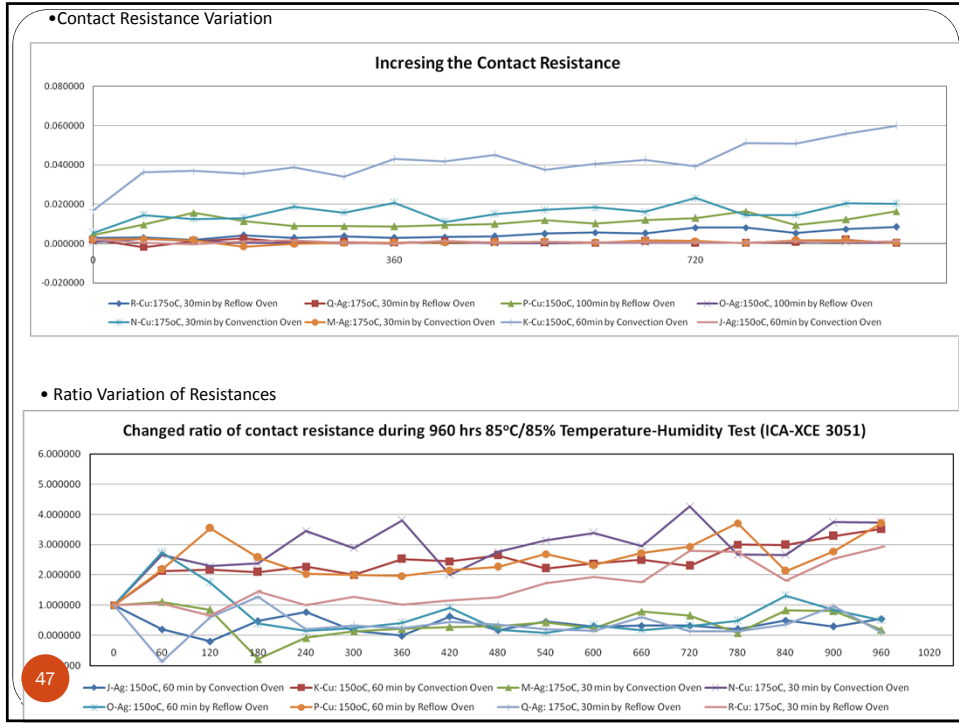


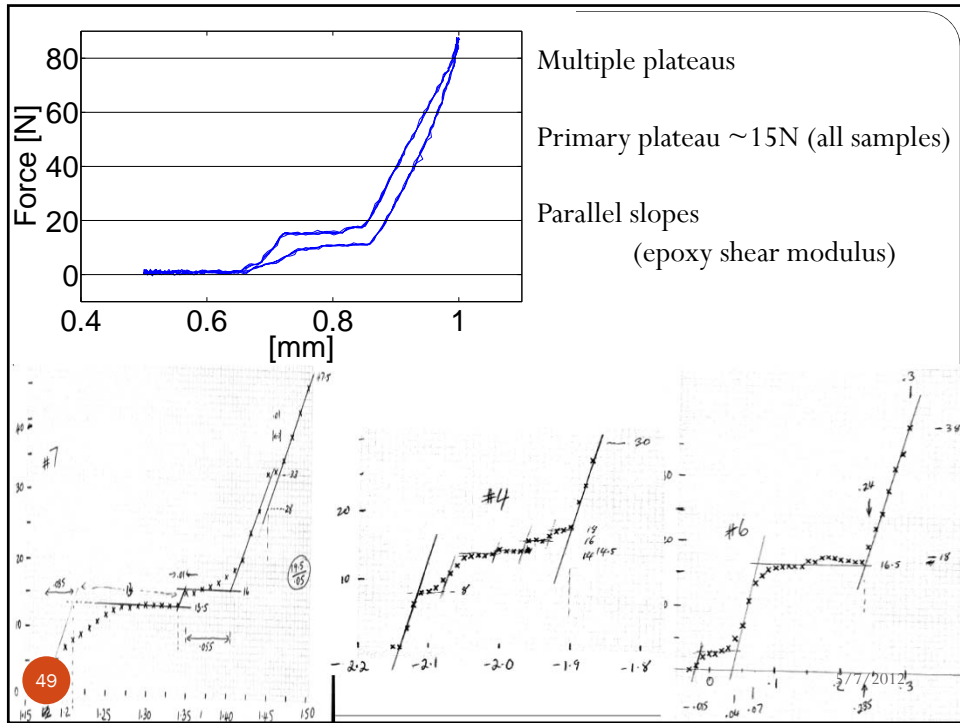
(Li & Morris)

ICA: Lee, Cho, & Morris, Proc. EMAP 2007

Ag-ICA 85/85 performance comparison on Cu and immersion-Ag PWB contacts







Cure Models

- Reaction rate $d\alpha/dt = K f(\alpha)$, where $K = A \exp(-E/RT)$
 - K = chemical rate constant, $f(\alpha)$ reactant concentration.
 - α = degree of cure
 - R = Gas constant = $8.31 \text{ J/K.mole} = Nk = 6.023 \times 10^{23} / \text{mole} \times 1.38 \times 10^{-23} \text{ J/K}$
- n-th order model: $f(\alpha) = (1 - \alpha)^n$
 - Calculate degree of cure (for constant T, i.e. isothermal cure):
 - 1st order: $d\alpha/dt = K(1 - \alpha)$, $\therefore \alpha = 1 - \exp(-Kt)$
 - 2nd order: $d\alpha/dt = K(1 - \alpha)^2$, $\therefore \alpha = 1 - [1 + Kt]^{-1}$
 - nth order: $d\alpha/dt = K(1 - \alpha)^n$, $\therefore \alpha = 1 - [1 + (n-1)Kt]^{-1/(n-1)}$
 - Rate proportional to reagent mass available
 - $n=1/2$ Phase boundary reaction (area)
 - $n=1/3$ Phase boundary reaction (volume)
 - $n=2/3$ Nucleation sphere (volume growth)
- Auto-catalyzed model:
 - Single-step: $d\alpha/dt = K f(\alpha) = K \alpha^m (1 - \alpha)^n$ but note $d\alpha/dt = 0$ for $\alpha = 0$
 - Double step (linear combination): $d\alpha/dt = (K_1 + K_2 \alpha^m)(1 - \alpha)^n$
 - Note: ONLY model with more than a single activation energy E
 - Modified double step: $d\alpha/dt = K f(\alpha) = K(y_1 + y_2 \alpha^m)(1 - \alpha)^n$ where $y_1 + y_2 = 1$

DSC: Directly determine degree of cure α and rate of cure $d\alpha/dt$

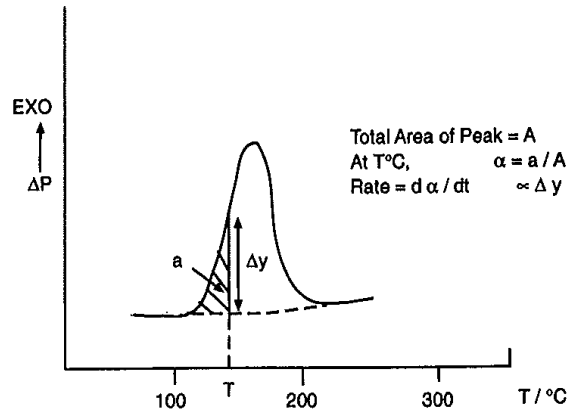
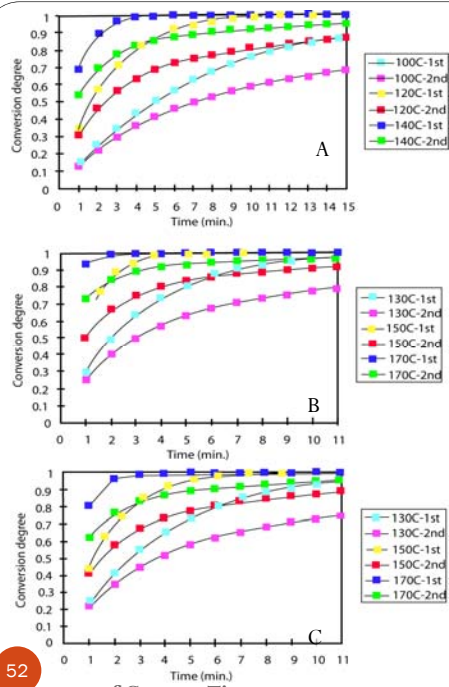
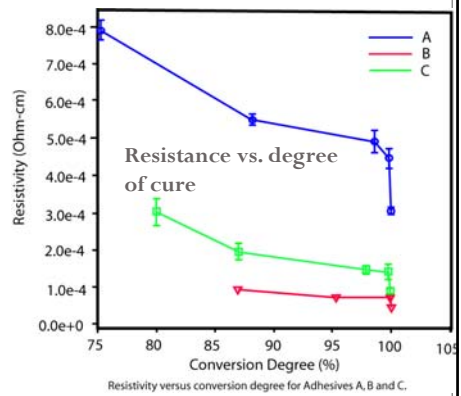


Figure 3.33 DSC curve for exothermic reaction showing measurement of partial and total areas.



Degree of Cure vs. Time

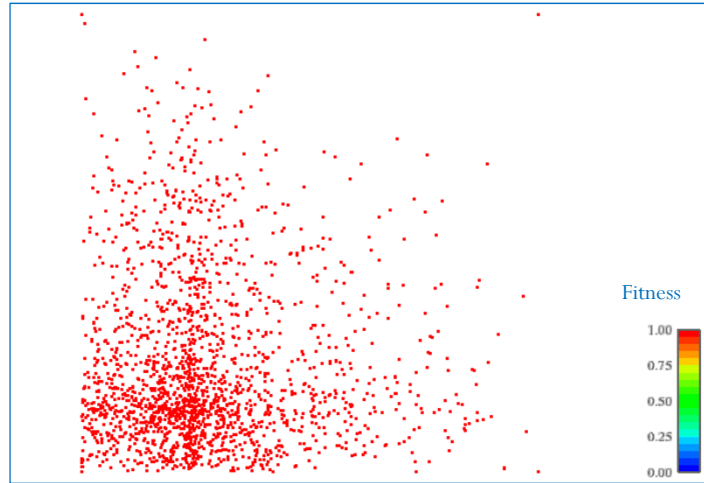
Cure Modeling: 3 Adhesives



Simple 1st order cure models work well

Manufacturer profiles → incomplete cure

Particle Swarm Optimisation



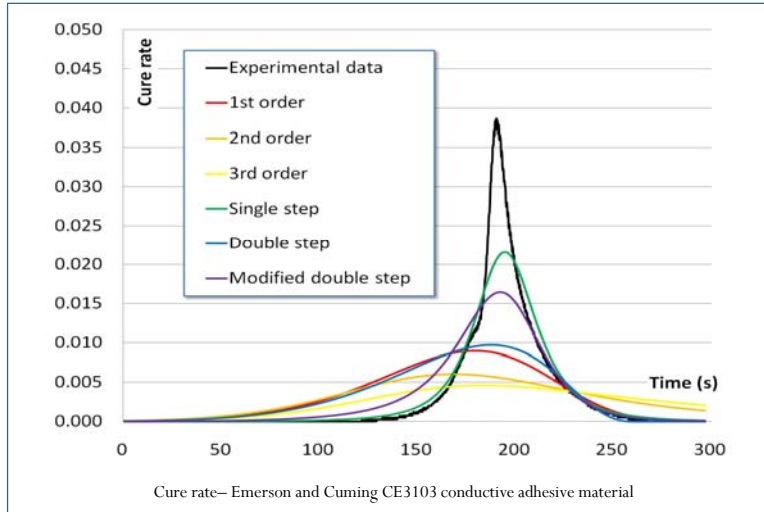
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Results – Optimal Coefficient Sets

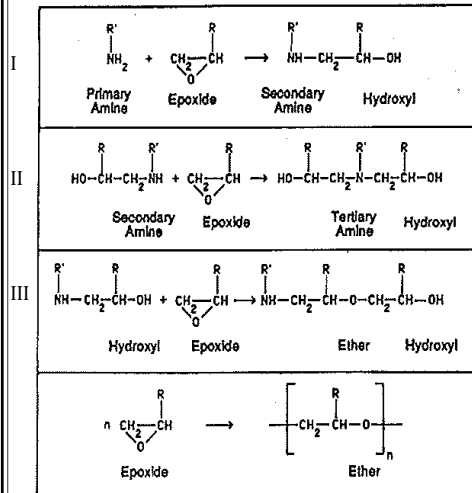
Model	E_1	A_1	n	m	E_2	A_2	γ_1
1 st order	37882	1021.64	1	-	-	-	-
2 nd order	35917	630.83	2	-	-	-	-
3 rd order	38364	841.82	3	-	-	-	-
Single step auto	31017	711.40	1.536	1.118	-	-	-
Double step auto	37039	666.04	0.767	3.958	309930	854.81	-
Modified double	33983	1074.40	1.326	1.115	-	-	0.0393

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Results – Cure variation



Basic (BADGE) curing reactions



- Etherification significant only at high T
- Model by 2-step auto-catalytic?
- For multiple reactions, e.g. 3 above

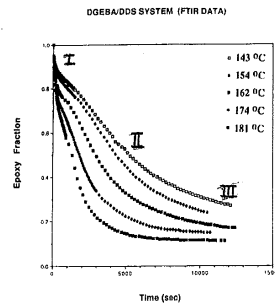
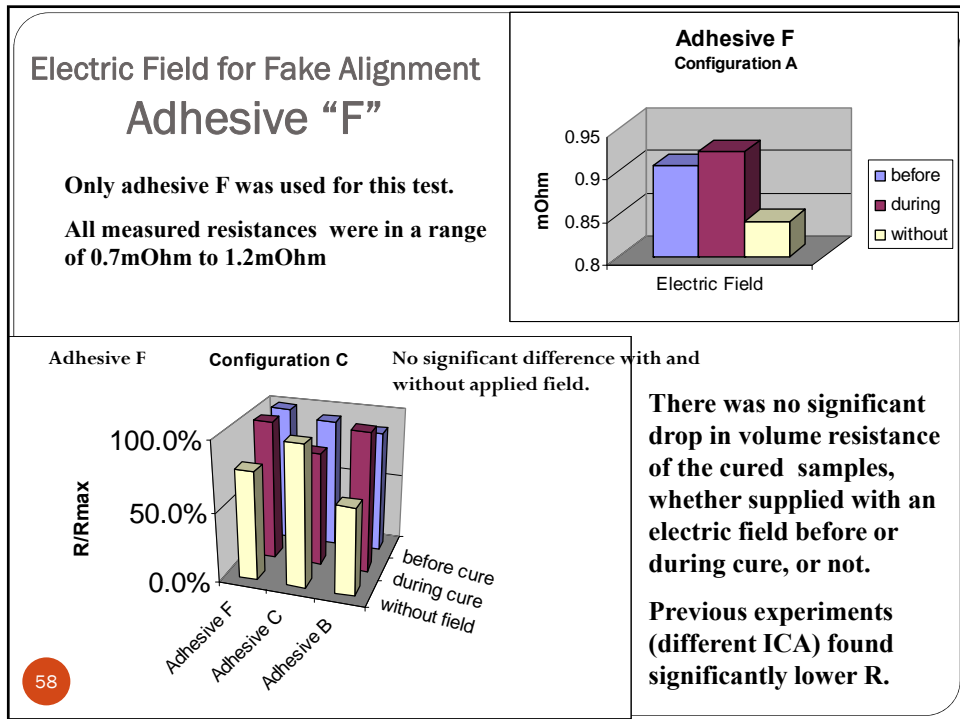
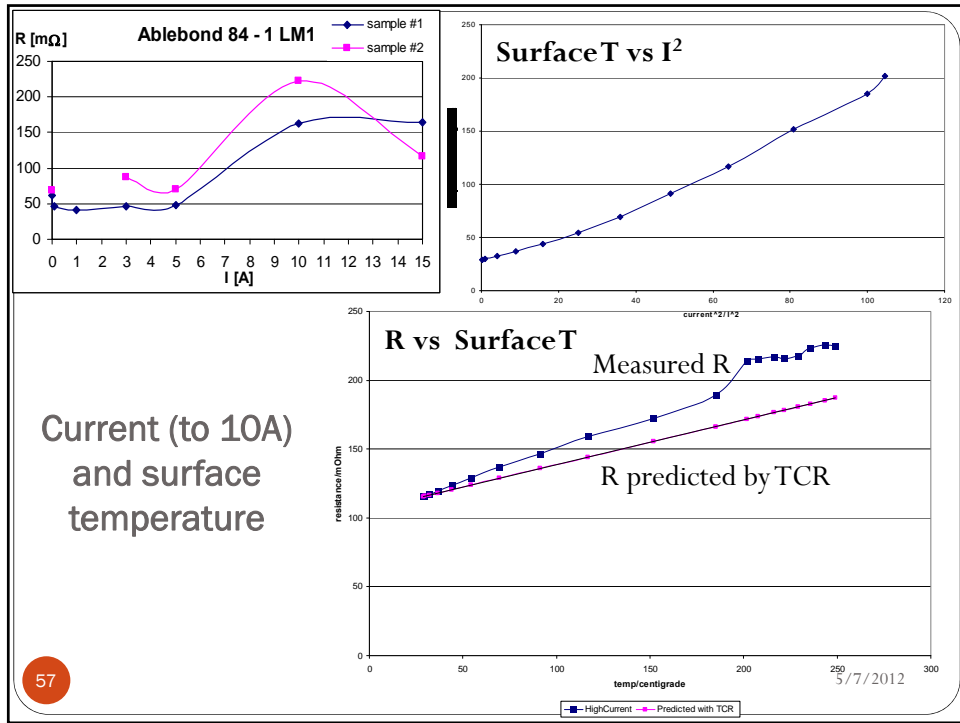


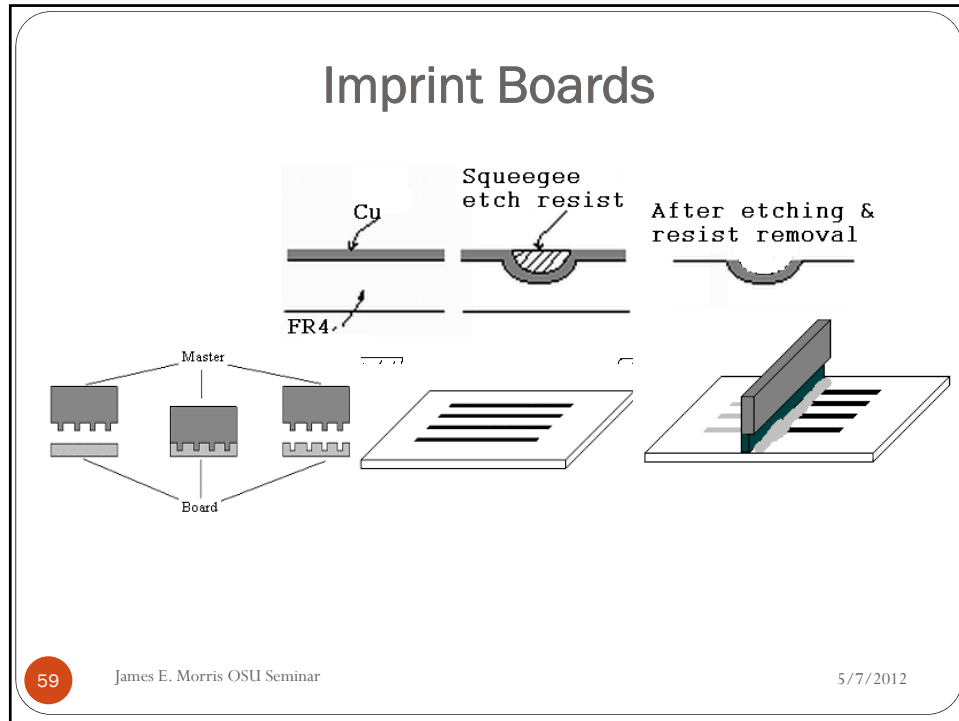
Figure 4. Results of transmission FTIR experiments during thermal cure based on changes in the 916-cm⁻¹ band.

Figure 1. Main reactions involved in the cure of epoxy resins with primary amine curing agents.

$$\frac{1}{K_{\text{effective}}} = \frac{1}{K_{\text{primary}}} + \frac{1}{K_{\text{secondary}}} + \frac{1}{K_{\text{etherification}}} + \frac{1}{K_{\text{diffusion}}} + \dots$$


$$\approx \frac{1}{K_{\text{primary}}} + \frac{1}{K_{\text{secondary}}} \text{ at low } T_{\text{cure}} > T_{\text{g}}$$






Summary: ICA

- Applications; processing
 - Cure modeling
- Electrical conduction
 - Sources of resistance; measurement; layering effects
 - TCR/frequency data
 - (Conduction modeling)
 - Nanoparticles (sintering) & CNTs
- Reliability issues
 - Impact resistance
 - Adhesion
- Continuing research
 - Cure modeling
 - Mechanical cycling
 - Drop test & crack propagation modeling



Nanoelectronics
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